

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:) **CONFIRMATION NO.: 3543**
)
Hiroki OHNO, et al.)
)
U.S. Serial No.: 10/594,549) **Group Art Unit: 1792**
)
Filed: September 27, 2006) **Examiner: Bibi S. Carrillo**

For: **SUBSTRATE CLEANING METHOD, SUBSTRATE CLEANING EQUIPMENT,
COMPUTER PROGRAM, AND PROGRAM RECORDING MEDIUM**

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir :

A response to the Office Action mailed October 29, 2009 is due by November 29, 2009.
The Action required restriction between two patentably distinct inventions.

Applicants hereby elect Group I of claims 1-17 and 21-24, drawn to a substrate cleaning method, for examination in this application. Applicants advise that no change in the inventorship of the application will be required by the eventual cancellation of non-elected claims.

Applicants reserve the right to file divisional application(s) for the non-elected claims in due course.

It is submitted that this application now is in condition for examination on the merits and early action in that regard is solicited.

Respectfully submitted,
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